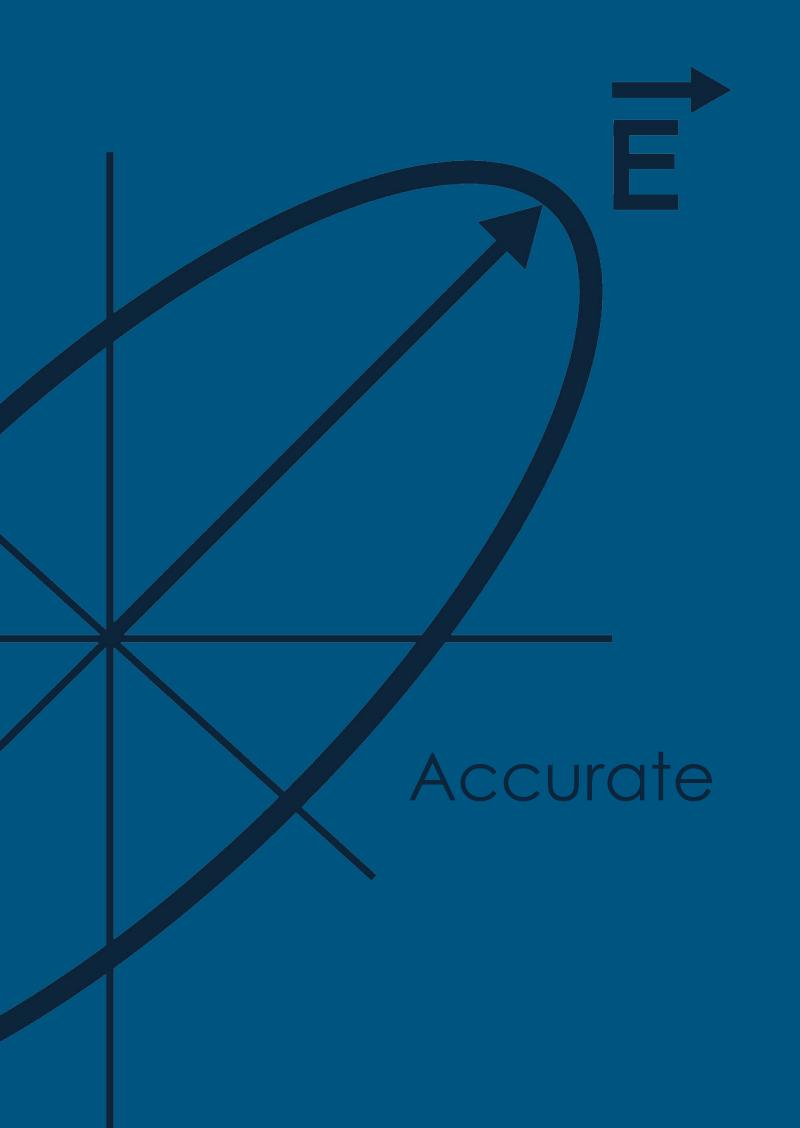
alpha-SE







Overview



The alpha-SE is a budget-friendly option for routine measurements of thin film thickness and refractive index in the visible spectral range.

Its compact footprint and simple accessories make the alpha-SE easy to use while harnessing the power of spectroscopic ellipsometry. It was designed for ease-of-use: simply place the sample on the stage, choose the model that matches your film, click "measure", and you will have results within seconds.

Why alpha-SE

+Easy-to-Use

Push-button operation is complemented by advanced software that takes care of the work for you.

+Powerful

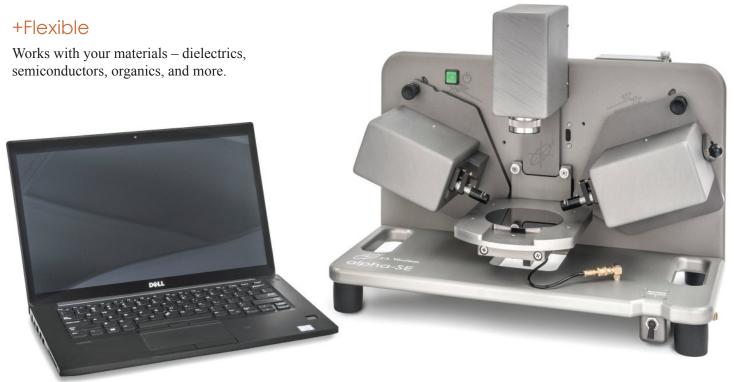
Proven spectroscopic ellipsometer technology gives you both thickness and refractive index with much higher certainty than other techniques.

+Affordable

Spectroscopic ellipsometry for simple sample systems.

+Fast

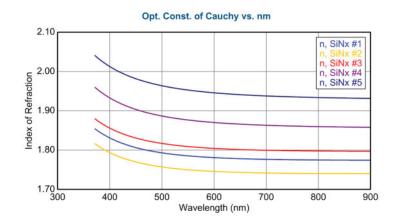
Hundreds of wavelengths simultaneously collected in seconds for immediate results.

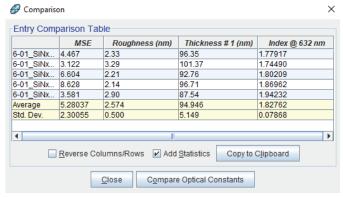


Applications

Transparent Films

With fast measurement speeds and push-button operation, the alpha-SE is ideal for qualifying transparent thin films. Single-layer dielectrics on silicon or glass substrates can be measured in seconds. Log results for easy-to-use comparisons in both graphical and tabular formats.





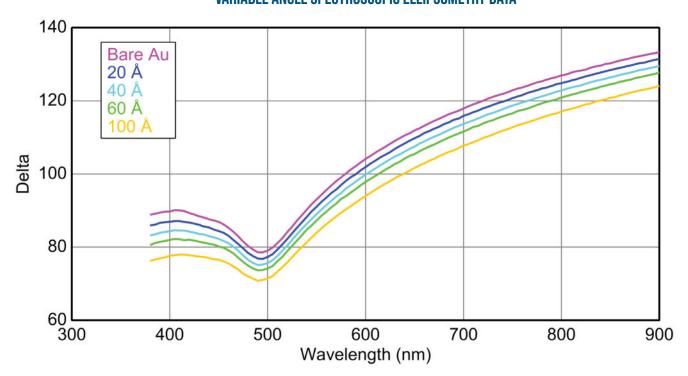
A series of silicon nitride thin films is quickly compared to study variation in the thickness and refractive index with process conditions.

Results can be easily compared in tabular form using our comparison tools.

Self-Assembled Monolayers

Phase information of a spectroscopic ellipsometry measurement is highly sensitive to very thin films (<10 nm). For example, self-assembled monolayers can be measured and quickly compared using the alpha-SE.

VARIABLE ANGLE SPECTROSCOPIC ELLIPSOMETRY DATA



For thin organic layers on gold, the phase parameter (Δ) shifts downward with increasing thickness.

Absorbing Films

Advanced models allow quick and efficient fits for a wide variety of absorbing materials.

Materials

- +a-Si
- +poly-Si
- +Diamond-like carbon
- +Organic Materials
- +Organic LED films
- +SiC
- +Photoresist
- +Display color filters
- +Metals

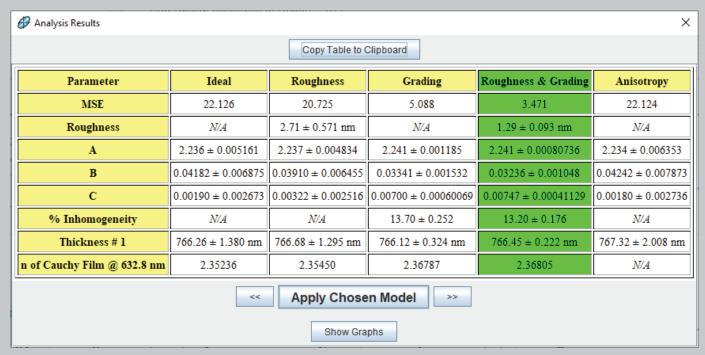
Models

- +Lorentz
- +Gaussian
- +Drude
- +Tauc-Lorentz
- +B-Spline



Coatings on Glass

Patented technology allows accurate measurements on any substrate: metal, semiconductor, or glass. For transparent substrates, the alpha-SE simultaneously measures depolarization to correct for light returning from the backside of the substrate. This unwanted light can confuse other ellipsometers, but the alpha-SE ensures accurate thickness and optical constants.

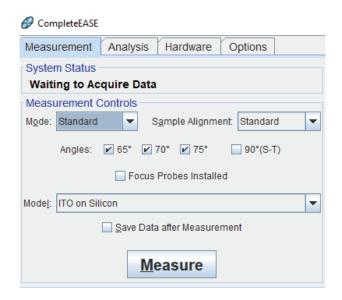


The high sensitivity of alpha-SE technology provides microstructural details that you cannot get from reflectance measurements. A thin film of Titanium Dioxide is measured with the alpha-SE, and its index is found to vary between the substrate and surface. A graded model with rough surface best describes this sample.

Easy Measurements

The alpha-SE was designed for ease of use and does not require extensive experience with ellipsometry to get the most out of the instrument. The instrument operates on our powerful CompleteEASE software to enable analysis of even the most complex samples. Measurement results can be achieved in just a few steps.

Three Simple Steps:



1. Mount your sample and choose your measurement settings:

- +Angles
- +Sample alignment
- +Model (optional)

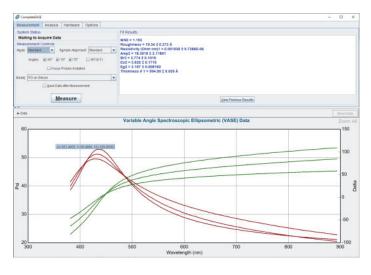
Setting up a measurement is easy. Select the preferred angles and alignment procedure. If a model has already been developed, it can be selected at this time as well.



2. Click 'Measure'

- +Align
- +Measure
- +Analyze

The sample is automatically aligned and measured. If a model was selected, the data will be automatically analyzed and results will be displayed immediately following the measurement.



3. Your results are reported:

- +Film thickness
- +Refractive index
- +Derived perameters

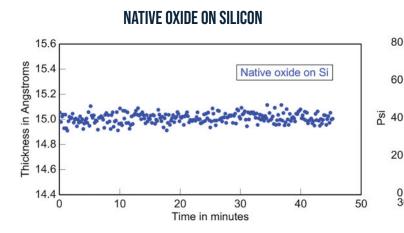
The results shown are determined by the model. The most commonly reported parameters are film thickness and refractive index. Ellipsometry is also sensitive to surface conditions, anisotropy, crystallinity, and more. Related parameters are reported if included in the model.

Thickness & Refractive Index

300

400

Spectroscopic ellipsometry is perfect for characterizing thin film thickness and refractive index. The alpha-SE can measure film thicknesses ranging from ultra-thin monolayers to several microns.



5-MICRON THICK OXIDE

270

Psi (65°)
Delta (65°)
Model

180

180

150

120 90

900

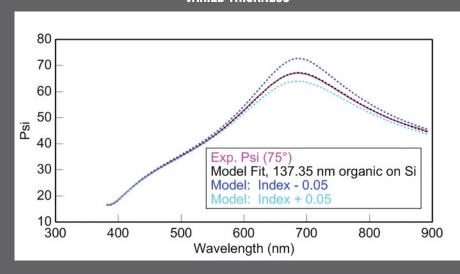
800

Dynamic measurements of a native oxide on silicon show very stable, sub-Angstrom precision.

This 5-micron thick oxide has a large number of interference features that are well-resolved by the alpha-SE.

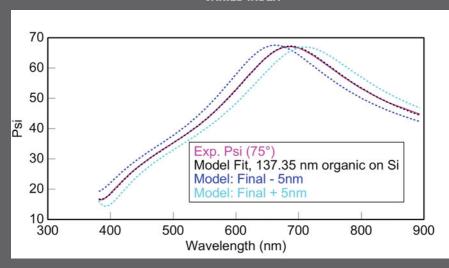
Wavelength (nm)

VARIED THICKNESS



An organic layer on silicon is easily characterized by the alpha-SE to determine thickness and refractive index. Simulated values with varied thickness and varied index (see graphs to the left) show the distinct changes that give ellipsometry unique results for both film properties.

VARIED INDEX





Accessories



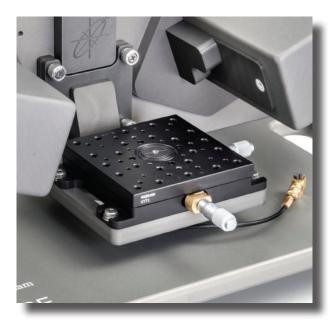
Focusing

- +Perfect for non-uniform or small samples
- +Reduce beam diameter to ~0.3 mm
- +Quick and easy magnetic attachment
- +No alignment or calibration required



Camera

- +View the focused beam measurement location
- +10 mm by 7 mm field of view
- +Integrated image within CompletEASE software



Translation

- +Fine adjustment of the measurement location
- +Manually adjust 12 mm XY range with .025 mm resolution
- +Integrated vacuum stage holds sample in place
- +Position the focused beam spot anywhere on the sample



Liquid Cell

- +Study samples in liquid ambients
- +500 µL liquid capacity
- +70° angle of incidence
- +Designed for glass slides & 1" or 2" wafers
- +Software accounts for window effects and index of ambient fluid



QCM Cell

- +Allows study of mechanical properties in liquid ambient
- +Tilt stage designed to hold Q-Sense QCM-D
- +J.A. Woollam provides mount only



Transmission Stage

- +Holds sample vertically to allow normal incidence transmission measurements
- +Tip-tilt stage for easy sample alignment
- +Integrated vacuum holds sample in place

Specifications

Spectral Range

380 nm to 900 nm, 180 wavelengths

Angle of Incidence

- +Manual adjustment
- +65°, 70°, 75°, or 90° (straight-through)

System Configuration

Patented rotating compensator technology with CCD detection

Sample Size

The alpha-SE accommodates samples up to 200 mm diameter and 16 mm thick.

Data Acquisition Rate

- +3 sec. (Fast mode)
- +10 sec. (Standard mode)
- +30 sec. (High-precision mode)

Software

CompleteEASE for data acquisition, data analysis, and optical simulations

Beam Diameter

+Standard: ~3 mm +Focused: ~0.3 mm

Power Requirements

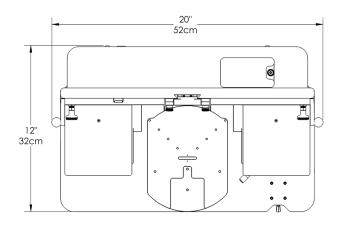
100/240 VAC, 47-63 Hz, < 1 Amp

Light Source

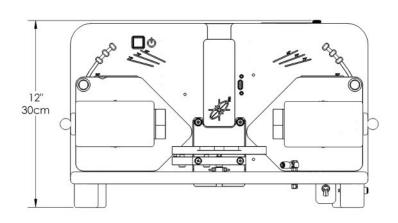
Quartz Tungsten Halogen (QTH)



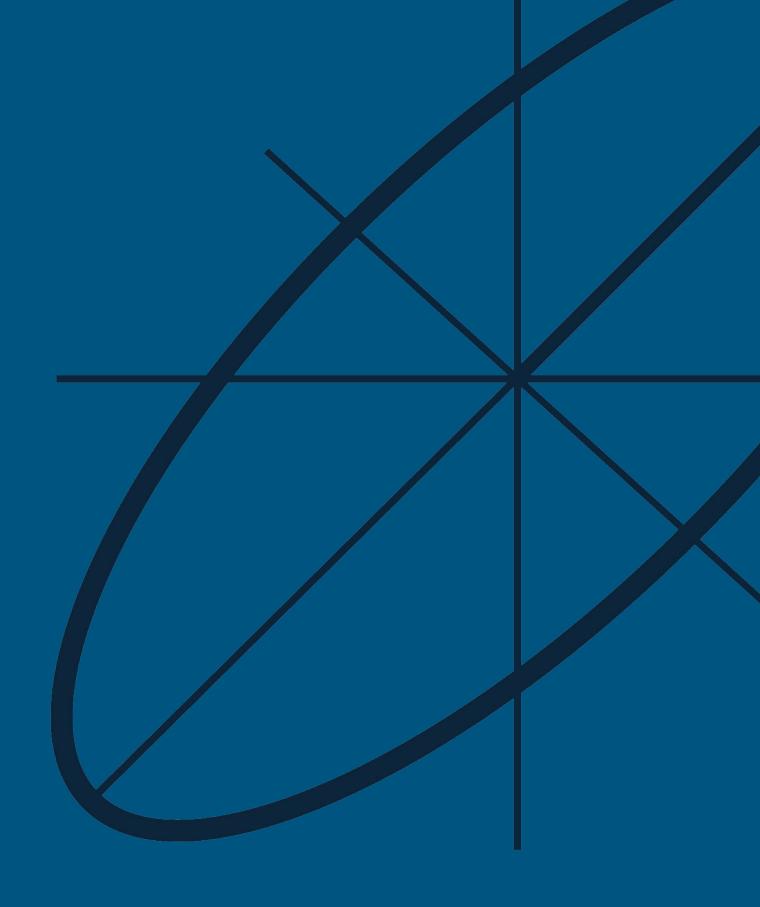
alpha-SE with camera and focusing accessories



Top View



Front View



Versatile

For more information:



